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PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

Docket No: Q76028

Yasuhiro IIJIMA

Appln. No.: 10/628,459

Group Art Unit: 3765

Confirmation No.: 4842

Examiner: Not yet assigned

Filed: July 29, 2003

For: **METHOD OF PRODUCING A POLYCRYSTALLINE THIN FILM AND A METHOD OF PRODUCING AN OXIDE SUPERCONDUCTING ELEMENT**

INFORMATION DISCLOSURE STATEMENT
UNDER 37 C.F.R. §§ 1.97 and 1.98

MAIL STOP AMENDMENT

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

Sir:

In accordance with the duty of disclosure under 37 C.F.R. § 1.56, Applicant hereby notifies the U.S. Patent and Trademark Office of the documents which are listed on the attached PTO/SB/08 A & B (modified) form and listed herein and which the Examiner may deem material to patentability of the claims of the above-identified application.

1. International Publication No. 01/29293, published April 26, 2001.
2. D F Lee et al. "Alternative Buffer Architectures for High Critical Current Density YBCO Superconducting Deposits on Rolling Assisted Biaxially-Textured Substrates", JAPANESE JOURNAL OF APPLIED PHYSICS, JAPAN SOCIETY OF APPLICATION PHYSICS, Tokyo, JP, vol. 38, no. 2B, 1999, pages L178-L180, XP000910949.

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U.S. Appln. No.: 10/628,459

3. Y. IIJIMA et al., "Ion Beam Induced Growth Structure of Fluorite Type Oxide Films for Biaxally Textured HTSC Coated Conductors", MATERIALS RESEARCH SOCIETY SYMPOSIUM PROCEEDINGS, MATERIALS RESEARCH SOCIETY, Pittsburg, PA, co. 585, 2000, pages 45-54, XP001119125.
4. U.S. Patent No. 6,150,034, issued November 21, 2000.
5. International Patent Publication No. 02/47119, published June 13, 2002.

One copy of each of the listed documents is submitted herewith, except for the following:

U.S. patents and/or U.S. patent publications; and co-pending non-provisional U.S. applications filed after June 30, 2003.

The present Information Disclosure Statement is being filed: (1) No later than three months from the application's filing date; (2) Before the mailing date of the first Office Action on the merits (whichever is later); or (3) Before the mailing date of the first Office Action after filing a request for continued examination (RCE) under §1.114, and therefore, no Statement under 37 C.F.R. § 1.97(e) or fee under 37 C.F.R. § 1.17(p) is required.

The present Information Disclosure Statement is being filed thirty days or fewer from the communication from a foreign patent office and a Statement Under 37 C.F.R. §1.704(d) is attached.

In compliance with the concise explanation requirement under 37 C.F.R. § 1.98(a)(3) for foreign language documents, Applicant encloses here with a copy of a corresponding European Search Report dated January 26, 2006 and an English translation of the pertinent portions thereof which cites such documents and indicates the degree of relevance found by the foreign office.

INFORMATION DISCLOSURE STATEMENT
U.S. Appln. No.: 10/628,459

The submission of the listed documents is not intended as an admission that any such document constitutes prior art against the claims of the present application. Applicant does not waive any right to take any action that would be appropriate to antedate or otherwise remove any listed document as a competent reference against the claims of the present application.

The USPTO is directed and authorized to charge all required fees, except for the Issue Fee and the Publication Fee, to Deposit Account No. 19-4880. Please also credit any overpayments to said Deposit Account.

Respectfully submitted,



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WASHINGTON OFFICE
23373
CUSTOMER NUMBER

Date: February 22, 2006



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STATEMENT UNDER 37 C.F.R. § 1.704(d)

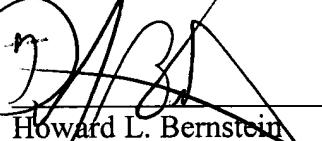
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

The undersigned hereby states, upon information and belief:

That each item of information contained in the Information Disclosure Statement filed concurrently herewith was cited in a communication from a foreign patent office in a counterpart foreign application, and that the communication was not received by any individual designated in 37 C.F.R. § 1.56(c) more than thirty days prior to the filing of said Information Disclosure Statement.

Respectfully submitted,



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WASHINGTON OFFICE
23373
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Substitute for Form 1449 A & B/PTO				Complete if Known	
INFORMATION DISCLOSURE STATEMENT BY APPLICANT <small>(use as many sheets as necessary)</small>				Application Number	10/628,459
				Confirmation Number	4842
				Filing Date	July 29, 2003
				First Named Inventor	Yasuhiro IIJIMA
				Art Unit	3765
				Examiner Name	Not yet assigned
Sheet 1 of 1		Attorney Docket Number		Q76028	

U.S. PATENT DOCUMENTS					
Examiner Initials*	Cite No. ¹	Document Number		Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document
		Number	Kind Code ² (if known)		
		US 6,150,034	A	11-21-2000	Paranthaman et al.
		US			

FOREIGN PATENT DOCUMENTS						
Examiner Initials*	Cite No. ¹	Foreign Patent Document		Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Translation ⁶
		Country Code ³	Number ⁴			
		WO	01/29293	A1	04-26-2001	
		WO	02/47119	A2	06-13-2002	The Regents of the University of California

NON PATENT LITERATURE DOCUMENTS					
Examiner Initials*	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city, and/or country where published.			Translation ⁶
		D F Lee et al. "Alternative Buffer Architectures for High Critical Current Density YBCO Superconducting Deposits on Rolling Assisted Biaxially-Textured Substrates", JAPANESE JOURNAL OF APPLIED PHYSICS, JAPAN SOCIETY OF APPLICATION PHYSICS, Tokyo, JP, vol. 38, no. 2B, 1999, pages L178-L180, XP000910949			
		IIJIMA et al., "Ion Beam Induced Growth Structure of Fluorite Type Oxide Films for Biaxially Textured HTSC Coated Conductors", MATERIALS RESEARCH SOCIETY SYMPOSIUM PROCEEDINGS, MATERIALS RESEARCH SOCIETY, Pittsburg, PA, co. 585, 2000, pages 45-54, XP001119125			

Examiner Signature		Date Considered	
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*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

¹Applicant's unique citation designation number (optional). ²See Kind Codes of USPTO Patent Documents at www.uspto.gov, MPEP 901.04 or in the comment box of this document. ³ Enter Office that issued the document, by the two-letter code (WIPO Standard ST. 3). ⁴For Japanese patent documents, the indication of the year of the reign of the Emperor must precede the serial number of the patent document. ⁵Kind of document by the appropriate symbols as indicated on the document under WIPO Standard ST. 16 if possible. ⁶Applicant is to indicate here if English language Translation is attached.